

2016 Spring Meeting, Lille May 2-6



European Materials Research Society

# Spring Meeting 2016

From May 2<sup>nd</sup> to 6<sup>th</sup>  
Lille Grand Palais - France

## Annealing of heavily boron-doped silicon: effect on electric and thermoelectric properties



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## **Introduction**

- Silicon as thermoelectric material
- State of the art

## **Experimental work**

- Seebeck measurements
- Hall measurements

## **Results**

- Thermal treatments effect
- Transport properties: the two mechanism model

## **Conclusions and perspectives**

# SILICON AS THERMOELECTRIC MATERIAL



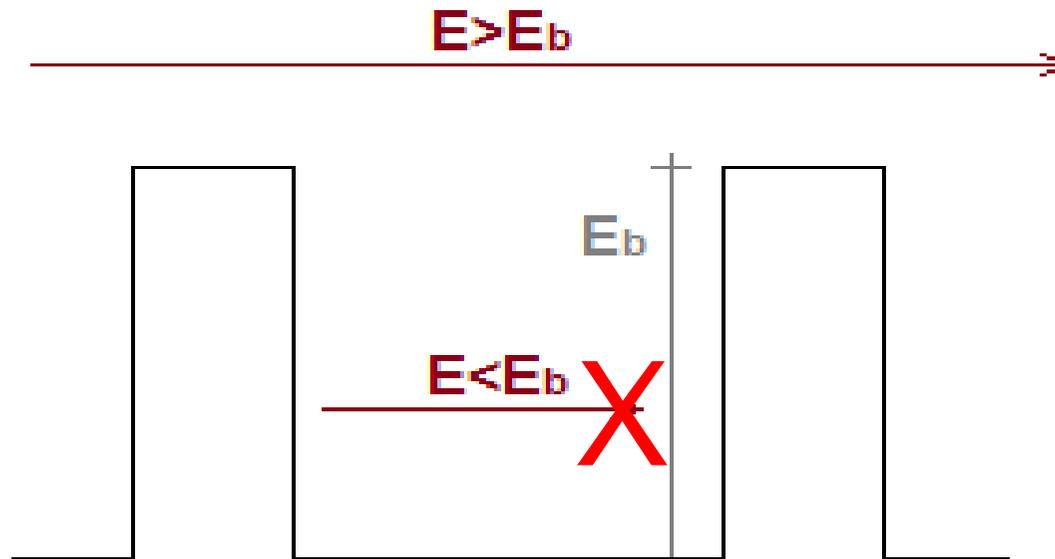
- Great abundance
- Low cost
- Huge know how of production and manipulation

**Poor thermoelectric performances**  
**Si figure of merit  $ZT \approx 0.01$**

$$ZT = \frac{S^2 \sigma}{k_e + k_{ph}} T$$

**Increasing power factor  $S^2\sigma$  through energy filtering**

# ENERGY FILTERING

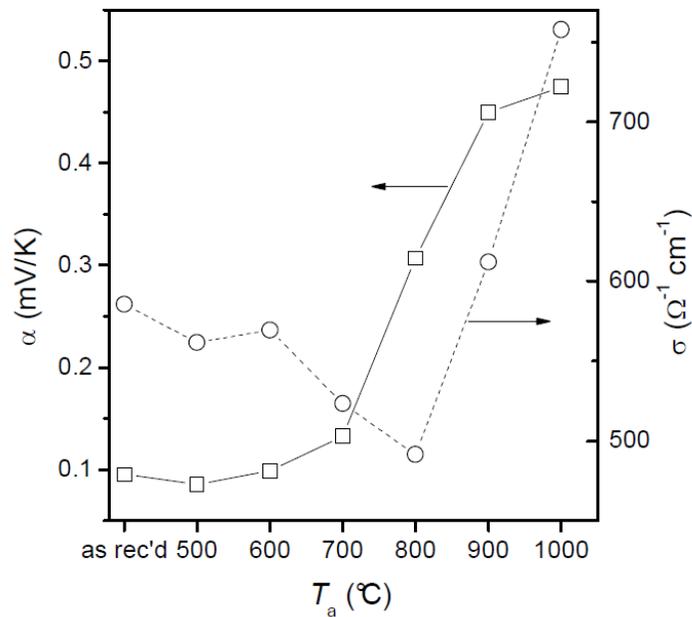
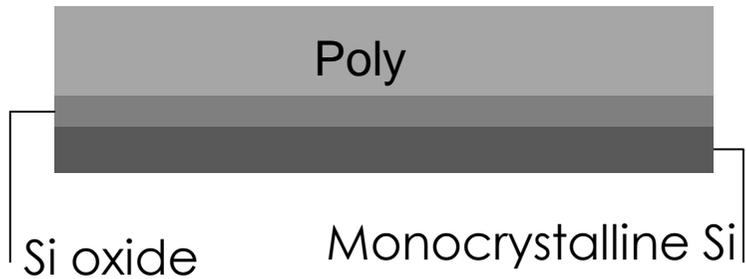


Seebeck coefficient can be increased  
eliminating low-energy carriers

N. Neophytou, et al; Journal of Electronic Materials **43**, 1896-1094 (2014)

# STATE OF THE ART

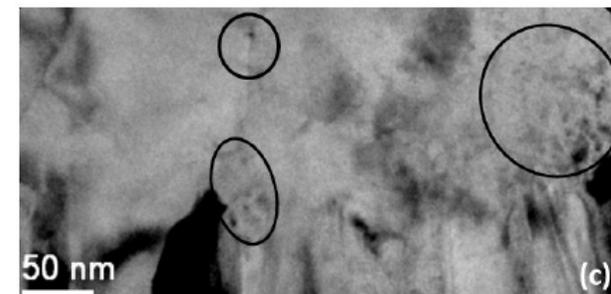
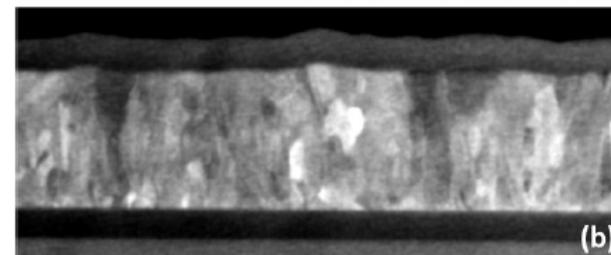
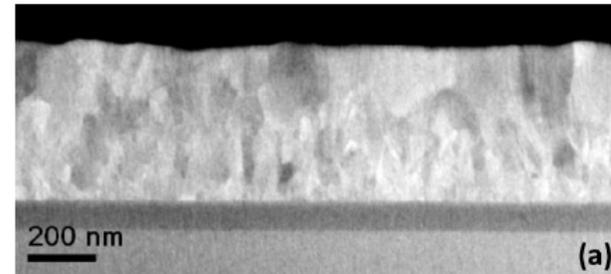
PolySi thin film (450-200 nm)



Annealing sequence  
from 500 to 1000 °C for 2 h

B. Lorenzi et al. Journal of ELECTRONIC MATERIALS, Vol. 43, No. 10, 2014

D. Narducci et al. Journal of Solid State Chemistry **193**, 19–25, (2012)



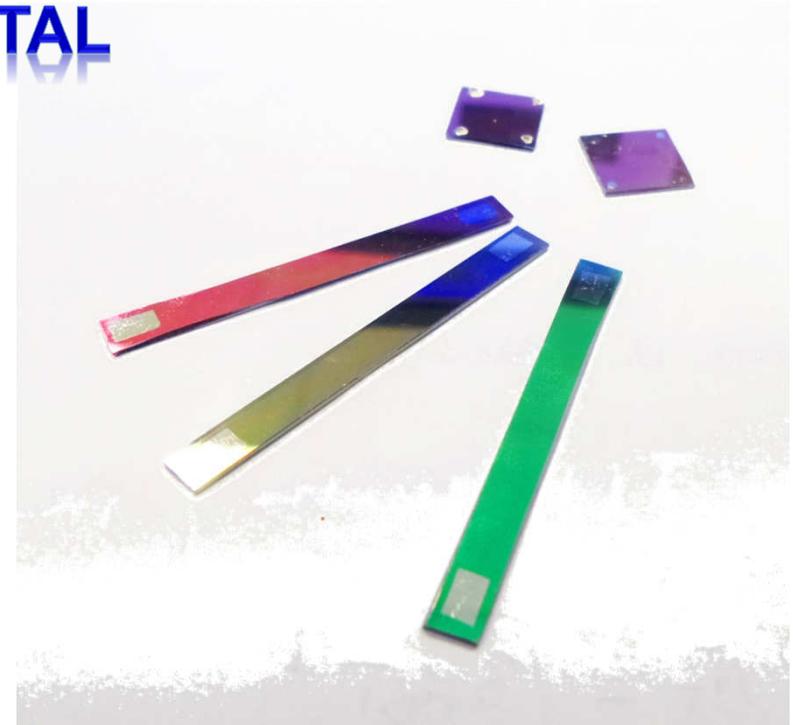
Formation of precipitates is  
evidenced by TEM images

# EXPERIMENTAL

Polycrystalline silicon  $d=228$  nm  
 Doping B  $4.4 \times 10^{20} \text{ cm}^{-3}$   
 Annealing in Ar following different protocols

Samples have been submitted to **different thermal treatment protocols** in order to evaluate the effect of annealing on different TE properties.

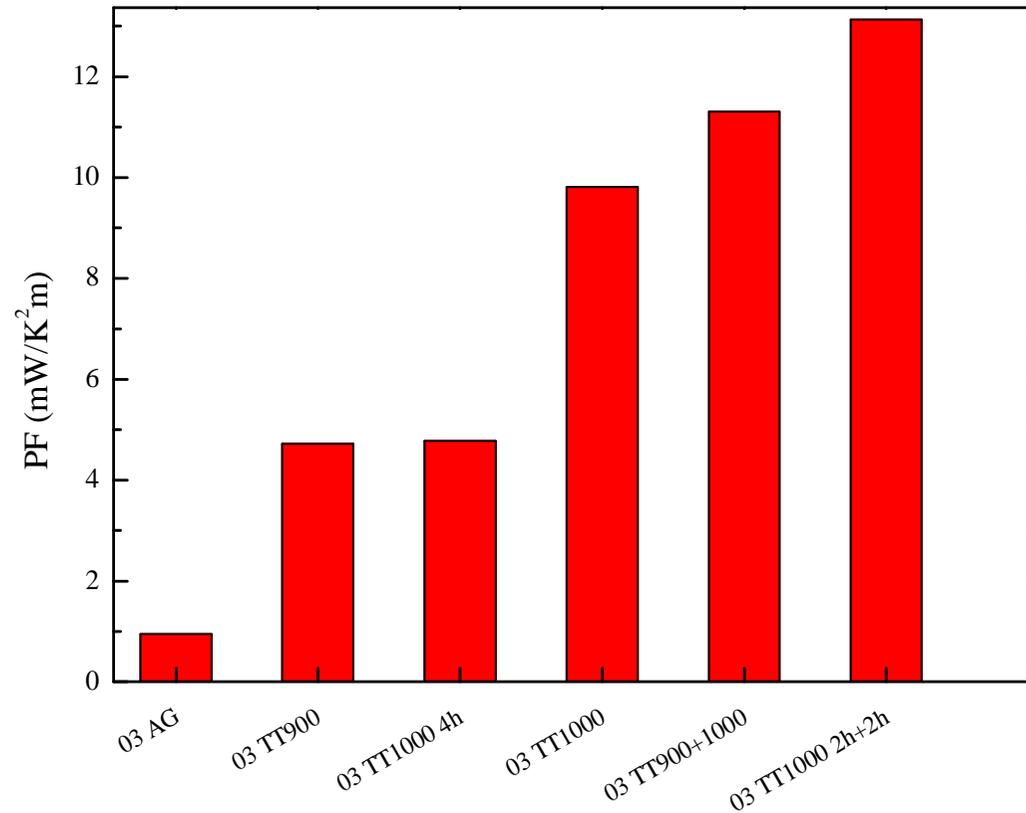
Sample	T=900 °C	T=1000 °C	T=1000 °C
AG	-	-	-
TT900(2)	2h	-	-
TT1000(2)	-	2h	-
TT900(2)1000(2)	2h	2h	-
TT1000(2+2)	-	2h	2h
TT1000(4)	-	4h	-



Seebeck sample: 5x50 mm  
 Hall sample: 12x12 mm

# POWER FACTORS

SAMPLE	Power Factor (mW/K <sup>2</sup> m)
AG	0.95
TT900(2)	4.72
TT1000(2)	9.82
TT900(2)1000(2)	11.31
TT1000(2+2)	13.13
TT1000(4)	4.78



Best result obtained for  
TT1000(2+2)

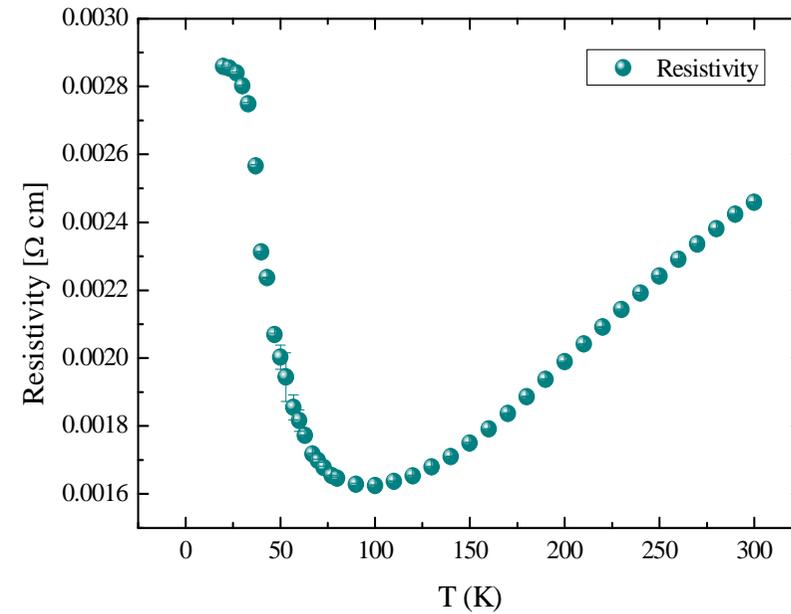
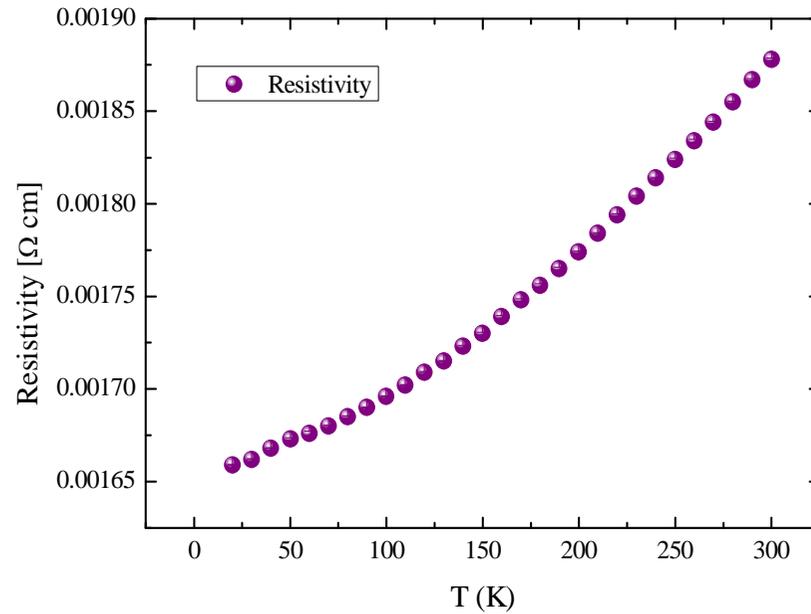
Duration of TT is not the only  
crucial parameter to be taken  
into account!!

# EFFECT OF THERMAL TREATMENTS

As grown Sample

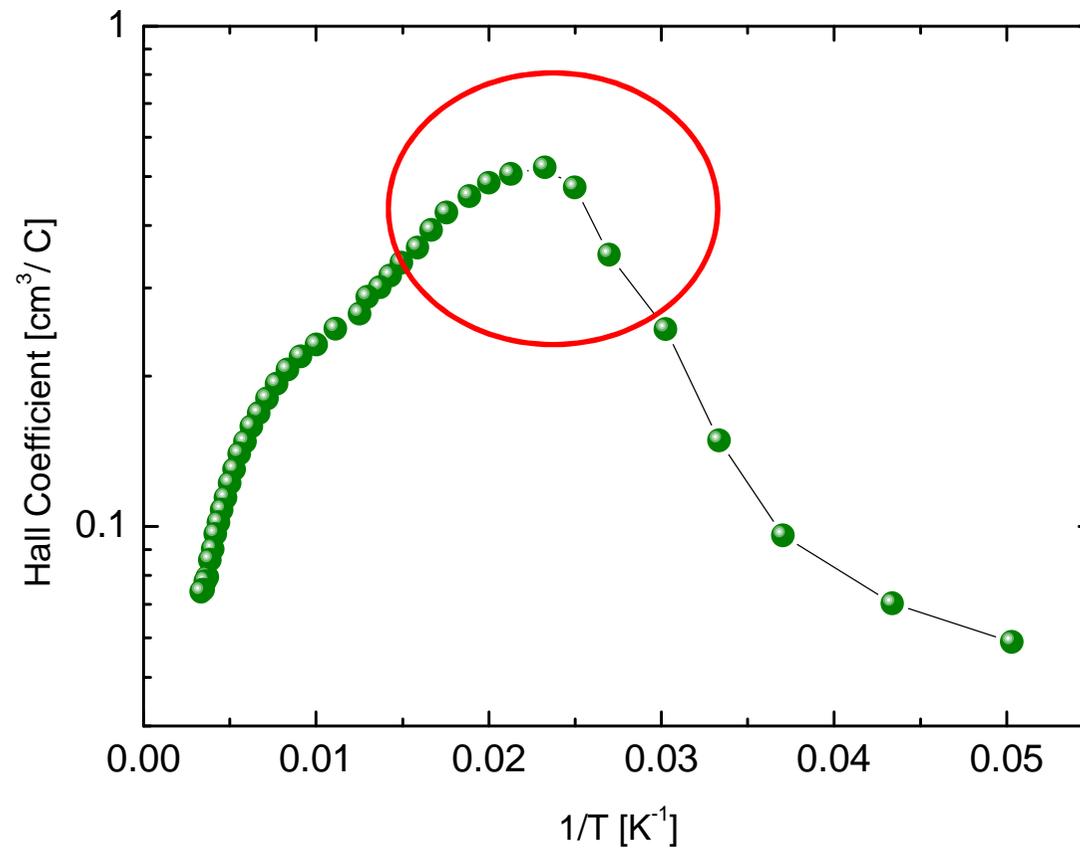


After thermal treatment

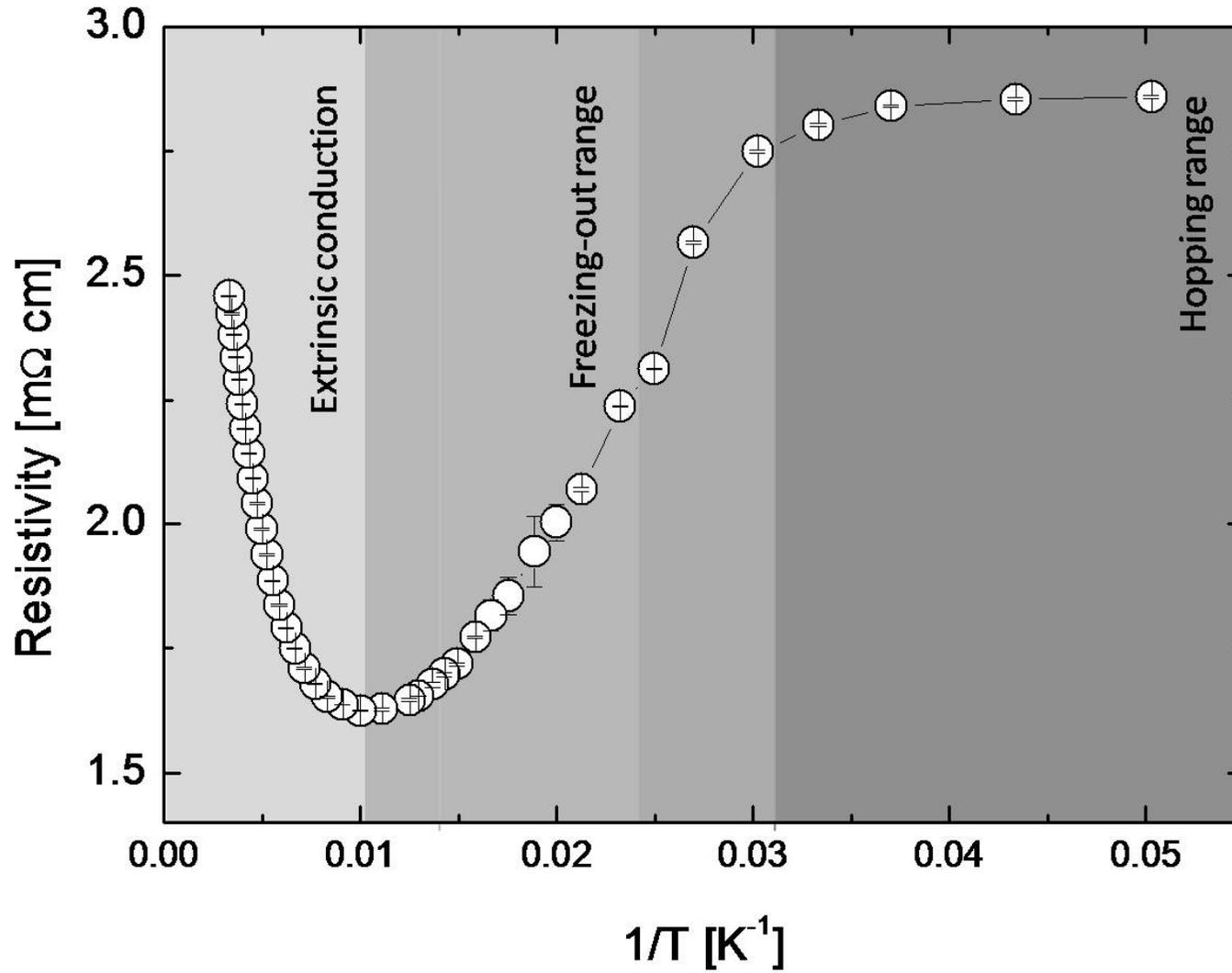


# EFFECT OF THERMAL TREATMENTS

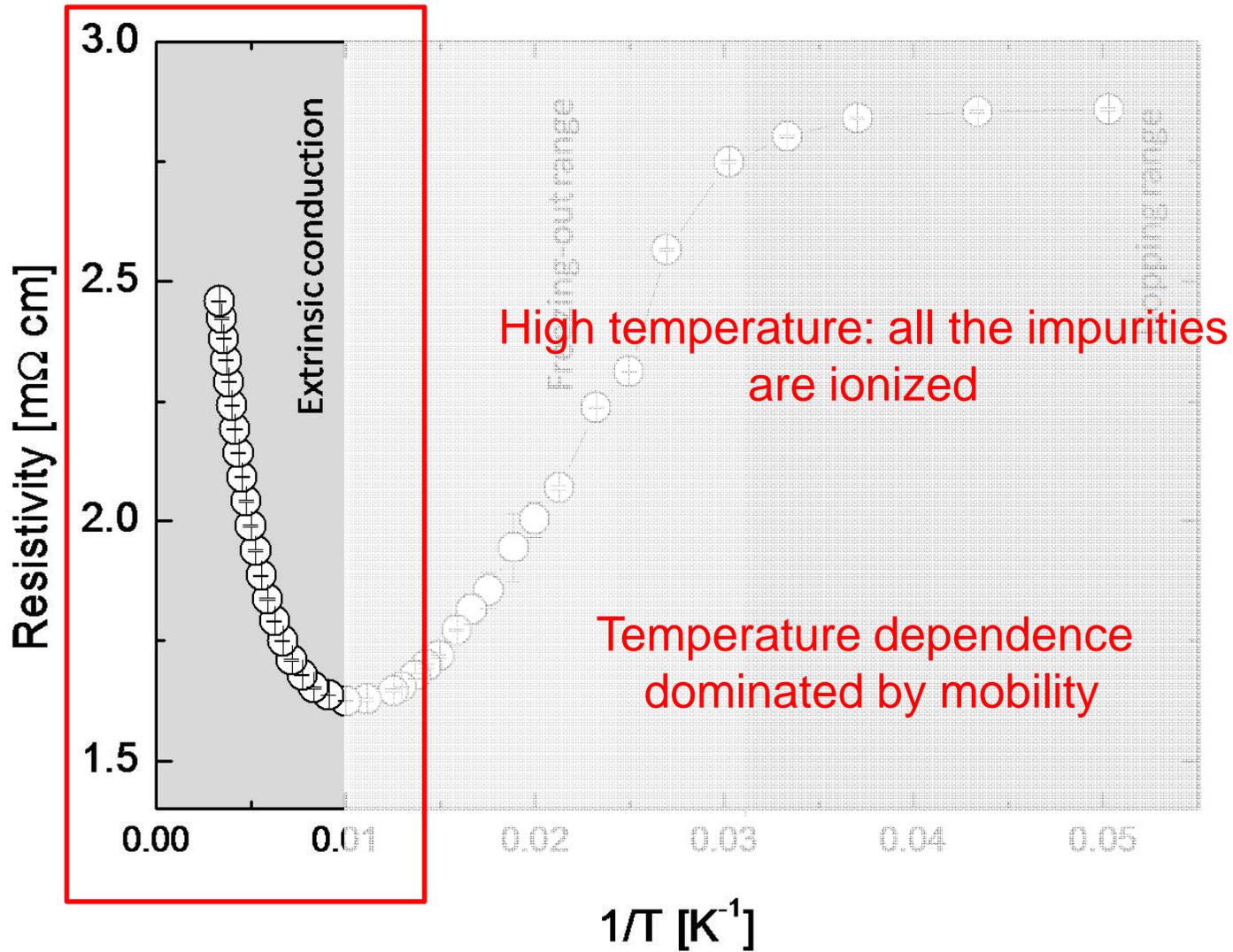
After thermal treatments: Hall coefficient  $R = \frac{F}{n_c e}$



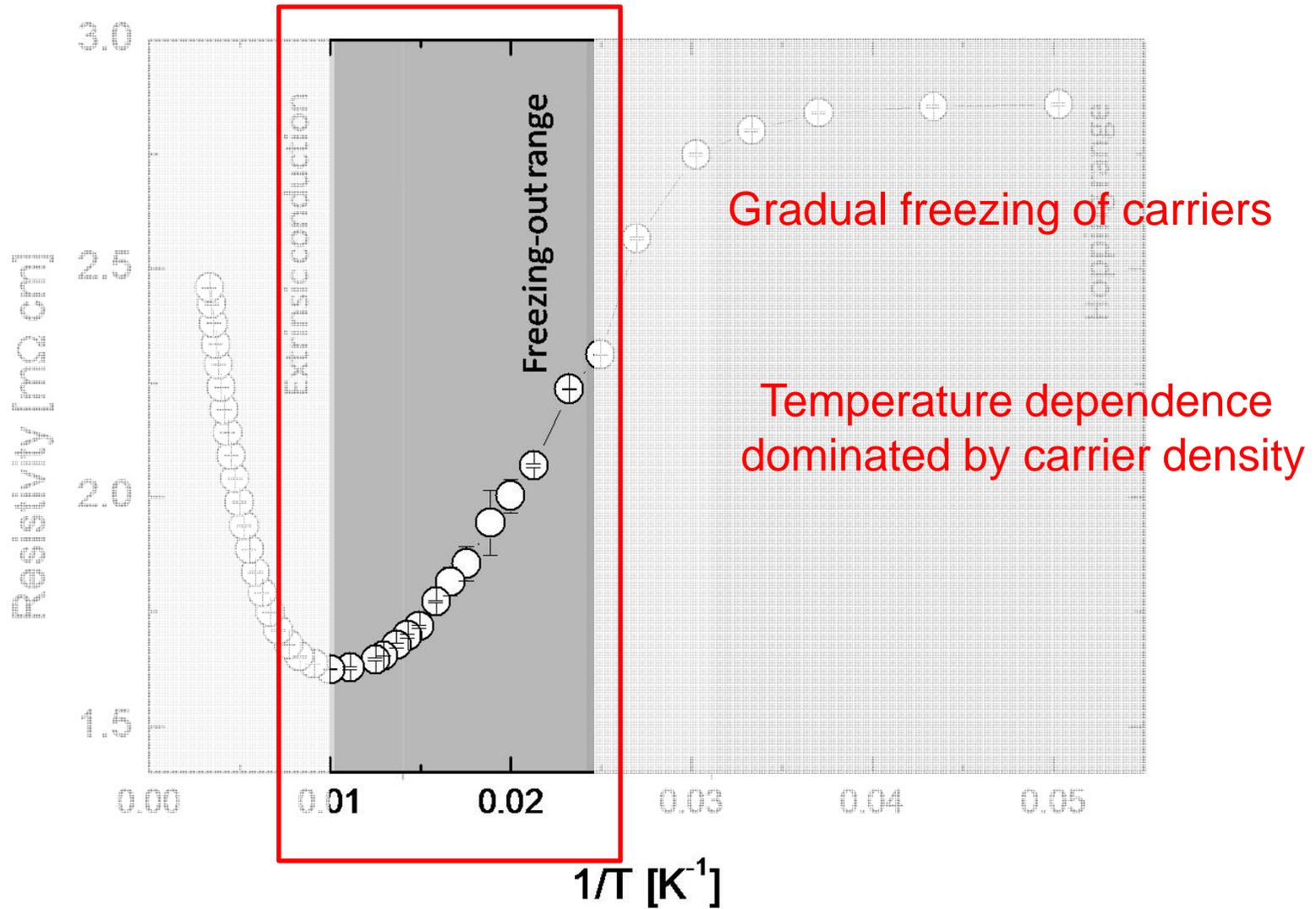
# CONDUCTION REGIMES



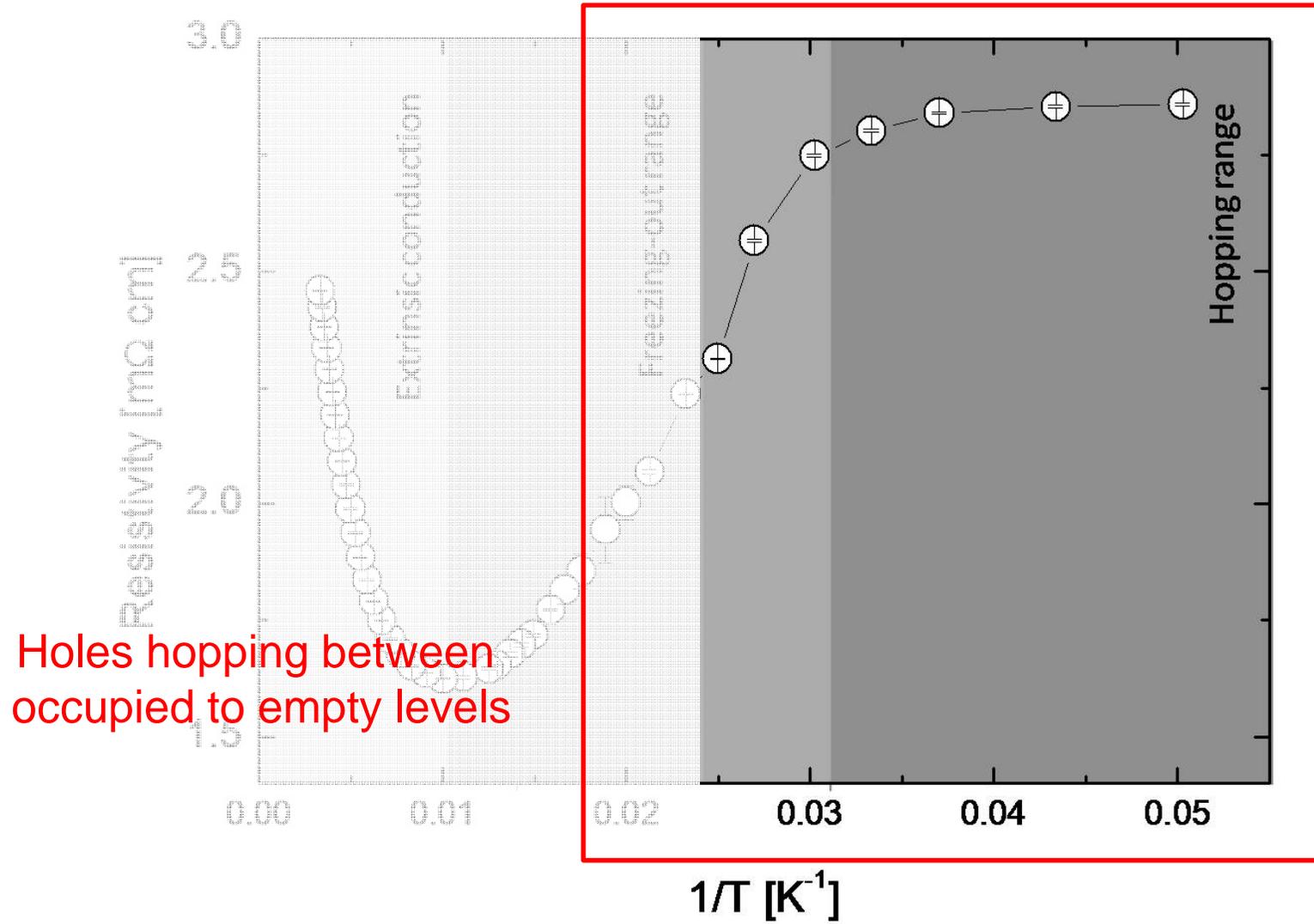
# CONDUCTION REGIMES



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# TWO COMPETING MECHANISM

Impurity semiconductor model (localized energy states)

$$\rho = \frac{1}{n_c e \mu_c}$$

$$R = \frac{F}{n_c e}$$

The model are not longer valid at low temperature!

Different kind of carriers plays a role with different mobility

- conduction band carriers:

$$\sigma_c, \mu_c = cR_c \sigma_c$$

- Hopping conduction carrier:

$$\sigma_h, \mu_h = cR_h \sigma_h$$

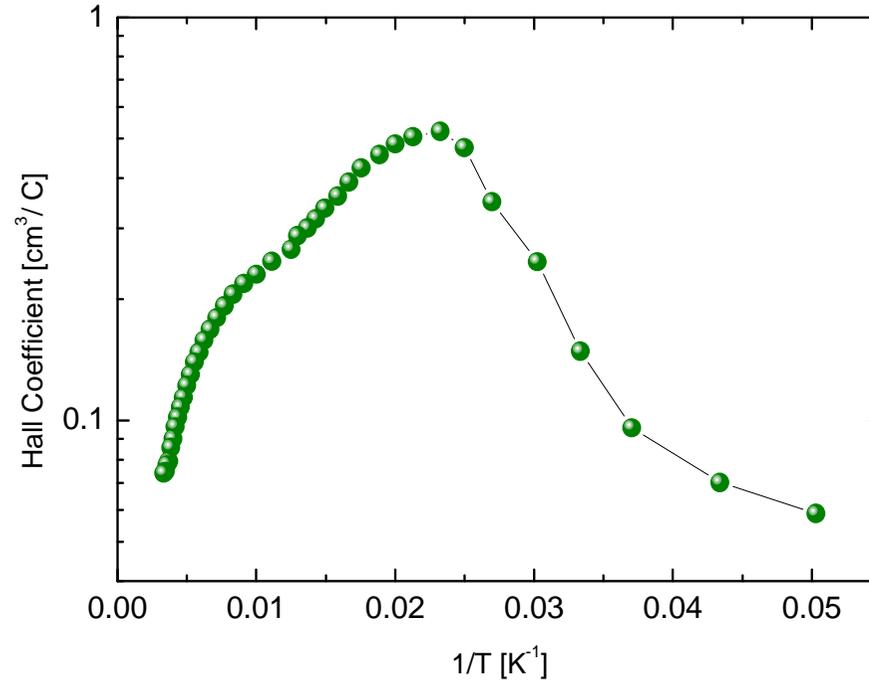
$$\rho = \frac{1}{n_c e \mu_c + n_h e \mu_h}$$

$$R = F \frac{n_c e \mu_c^2 + n_h e \mu_h^2}{(n_c e \mu_c + n_h e \mu_h)^2}$$

# HALL COEFFICIENT

$$R_{c,h} = \frac{1}{en_{c,h}} \quad \sigma_{c,h} = n_{c,h} e \mu_{c,h}$$

$$R = \frac{R_c \sigma_c^2 + R_h \sigma_h^2}{(\sigma_c + \sigma_h)^2}$$



If  $\mu_h \ll \mu_c$

$$R \approx \frac{R_c \sigma_c^2}{(\sigma_c + \sigma_h)^2}$$

We have a maximum for  $\sigma_h \approx \sigma_c$

# HALL COEFFICIENT

In the low temperature limit  $n_c = 0$  →  
(all the carrier are in the impurity band)

$$R = F \frac{1}{n_h e} \approx \frac{1}{ne}$$

In the high temperature limit  $n_h = 0$  →  
(all the carrier are in the conduction band)

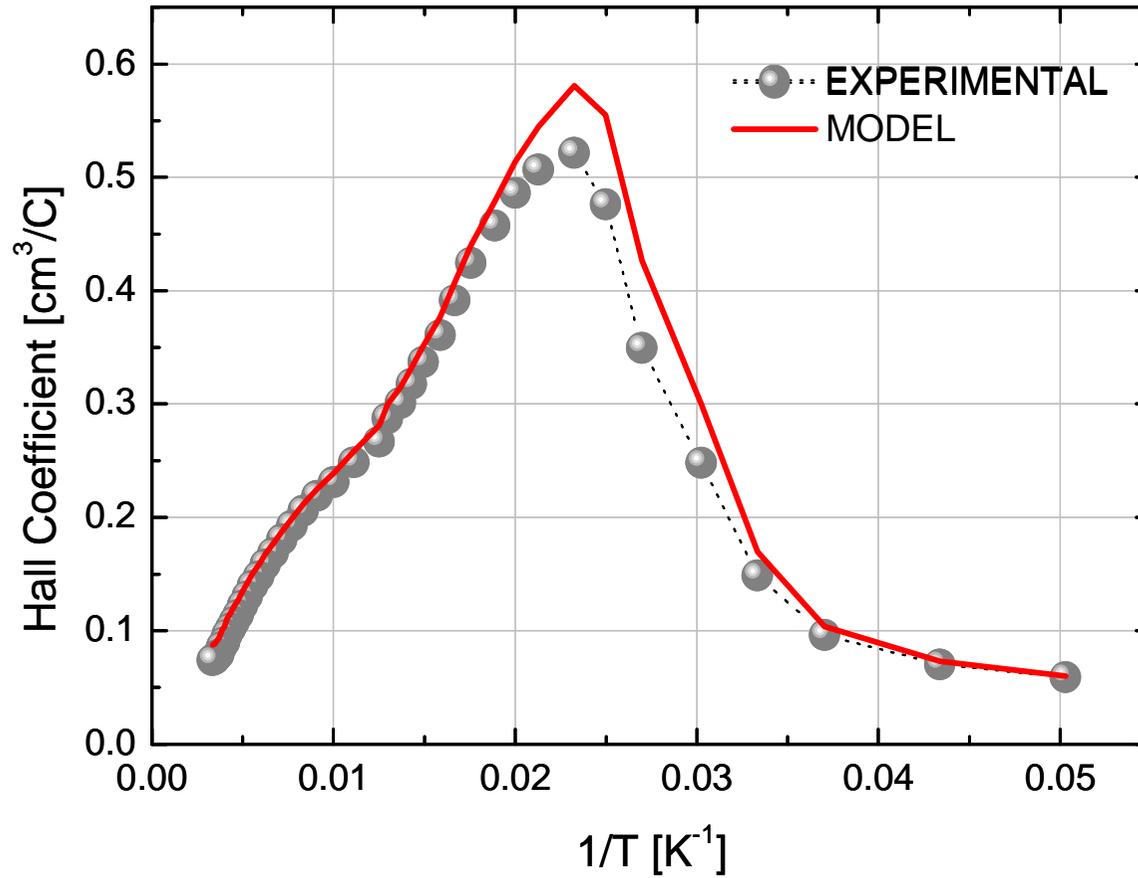
$$R = F \frac{1}{n_c e} \approx \frac{1}{ne}$$

We expect the value of R to be the same  
at low and high temperature

$$R_{LT}^{EXP} = 0.070 \pm 0.002$$

$$R_{HT}^{EXP} = 0.074 \pm 0.002$$

# MODEL VS EXPERIMENTAL DATA



## CONCLUSIONS

- ✓ Study on the annealing effect on TE performances heavily doped nanocrystalline silicon thin film
- ✓ Best performances for double thermal treatments at 1000 °C (power factor 13.13 mW/ K<sup>2</sup> m)
- ✓ The model used for homogeneous system is not longer valid at low temperature
- ✓ From resistivity measurements we can distinguish between three different conduction regime in temperature
- ✓ A simply model (two conduction mechanism) reproduces experimental data
- ✓ Relation between TE performances and transport mechanism is still unknow
- ✓ Further investigation and ad hoc model are needed!



## Thermoelectrics Research Group

Prof. Dario Narducci  
Laura Zulian  
Bruno Lorenzi  
Daniela Galliani



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